«Saint Petersburg OPEN 2017»



BOOK of ABSTRACTS

4th International School and Conference on Optoelectronics, Photonics, Engineering and Nanostructures

April 3 – 6, 2017 • Saint Petersburg, Russia

"Saint Petersburg OPEN 2017"

4th International School and Conference on Optoelectronics, Photonics, Engineering and Nanostructures

St. Petersburg, Russia, April 3 - 6, 2017

BOOK of ABSTRACTS



Academic University Publishing St. Petersburg, 2017

Copyright © by 2017 St. Petersburg Academic University and individual contributors. All

rights reserved. No parts of this electronic publication may be multiple copied, stored in a retrieval system or transmitted in any form or by any means, electronic, mechanical,

photocopying, recording or otherwise, without the written permission of the publisher.

Single photocopies of single articles may be made for private study or research.

4th International School and Conference "Saint Petersburg OPEN 2017"

Optoelectronics, Photonics, Engineering and Nanostructures carries on the tradition of annual conferences and schools organized at St Petersburg Academic University for

students, PhD students and young scientists. The School and Conference is established

and chaired by Nobel Prize laureate in Physics academician Zhores Alferov.

More detailed information on the School and Conference is presented on

http://spbopen.spbau.com/

The Book of Abstracts includes abstracts of contributed works accepted for presentation

at the Conference.

The volume was composed by St. Petersburg Academic University from electronic files

submitted by the authors. Only minor technical corrections were made by the composers.

Chief Editor: Zh. I. Alferov

Editors: A. E. Zhukov, V. V. Korenev

Published by

St. Petersburg Academic University, Khlopina 8(3),

194021 St Petersburg, Russia

Printed in Russian Federation

3

Organizers



St. Petersburg Academic University



Peter the Great St Petersburg Polytechnic University

Acknowledgements





SPIE STUDENT CHAPTER

SAINT-PETERSBURG ACADEMIC UNIVERSITY RUSSIAN ACADEMY OF SCIENCES



IOP Institute of Physics

Head of Program Committee

Zhores I. Alferov

Academician, Vice-President of the RAS, Chairman of St Petersburg Scientific Centre of the RAS, Rector of St Petersburg Academic University

Program Committee

Michael V. Dubina, academician, Head of Nanobiotechnologies Lab

(St Petersburg Academic University, Russia)

Alexey E. Zhukov, corr. member of the RAS, Head of Nanophotonics Lab and

Vice-rector (St Petersburg Academic University, Russia)

Andrey A. Lipovskii (Peter the Great St. Petersburg Polytechnic University, Russia)

Alexander V. Omelchenko (St Petersburg Academic University, Russia)

Vladimir G. Dubrovskii, Prof. Head of Physics of Nanostructures Lab

(St Petersburg Academic University, Russia)

Head of Organizing Committee

Alexey E. Zhukov (St Petersburg Academic University, Russia)

Organizing Committee

Alexander V. Omelchenko (St Petersburg Academic University, Russia)

Mikhail V. Maximov (Ioffe Institute, St Petersburg Academic University, Russia)

Andrey A. Lipovskii (Peter the Great St.Petersburg Polytechnic University, Russia)

George E. Cirlin (St Petersburg Academic University, Russia)

Valentina V. Zhurikhina (Peter the Great St. Petersburg Polytechnic University, Russia)

Vladimir V. Korenev (St Petersburg Academic University, Russia)

Eduard I. Moiseev (St Petersburg Academic University, Russia)

Julia S. Polubavkina (St Petersburg Academic University, Russia)

Invited Speakers

Alexey Toropov, M V Rakhlin, K G Belyaev, S V Sorokin, G V Klimko, S V Gronin, I V Sedova, I S Mukhin, T V Shubina, S V Ivanov
Micro- and nanofluidic systems in devices for biological, medical and ecological diagnostics Anatoly Evstrapov
Semiconductor light sources for near- and mid-infrared spectral ranges Leonid Karachinsky
Chemical vapor deposition of gallium nitride and oxynitride layers Sergei Alexandrov
Terahertz lasers based on semiconductor nanostructures Sergey Morozov, V V Rumyantsev, A V Ikonnikov, A A Dubinov, M A Fadeev, A M Kadykov, K E Kudryavtsev, N N Mikhailov, S A Dvoretckiy, V I Gavrilenko, I I Zasavitskii, A U Pavlov, N V Schavruk, R A Khabibulin, R R Reznik, G E Cirlin, F I Zubov, A E Zhukov, J I Alferov52
Crystal growth and structural properties of nanostructures
1-01 Separation of Ga-polar GaN layer from Si substrate by wet chemical etching Kseniya Shubina, T Berezovskaya, D Mokhov, A Mizerov, E Nikitina44
1-02 Preparation of a silicon surface for subsequent growth of dilute nitride alloys by molecular-beam epitaxy Alexandra Lazarenko, T Berezovskaya, D Denisov, M Sobolev, E Pirogov, E Nikitina
1-03 Simulation of the formation of polymorphic varieties of nanodiamonds Vladimir Greshnyakov, E Belenkov
1-04 Highly conductive indium nanowires deposited on silicon by dip-pen nanolithography Anton Kozhukhov, D Shcheglov, A Latyshev
1-05 WO3 and Mo:WO3 films produced by an aqueous sol-gel method Jolanta Raudoniene, J Raudoniene, A Laurikenas, M Kaba, S Gozde, A Morkan, R Seidu, A Kareiva, E Garskaite
1-06 Influence of annealing temperature on the upconversion luminescence properties of NaYF4:Er,Yb@SiO2 particles Elena Sagaidachnaia, V Kochubey, J Konyukhova
1-07 Novel approach for III-N on Si (111) templates fabrication by low-temperature PA MBE using porous Si layer Dmitrii Zolotukhin, P Seredin, A Lenshin, D Gloshchapov, A Mizerov
1-08 Quantum dot based superstructures: optical anysotropy Dominika Volgina, E Ushakova, A Fedorov, A Baranov
1-09 Germanium layers grown by zone thermal crystallization from a discrete liquid source

Graf, B Laikhtman
5-05 Photoelectric properties of SiC/Si structure grown by the method of atoms substitution Aleksandr Grashchenko, N Feoktistov, A Osipov, E Kalinina, S Kukushkin
5-06 The electronic structure of magnetic d-ions in manganese doped copper metaborate Cu1-xMnxB2O4 Anastasiia Molchanova, K Boldyrev
5-07 Terahertz spectroscopy of multiferroic PrFe3(BO3)4: electron-phonon interaction in external magnetic field Kirill Boldyrev,
5-08 Formation and research of spin light-emitting diodes based on structures with a GaMnAs injector Mikhail Ved, E Malysheva, M Dorokhin, A Zdoroveyshchev
5-09 Scanning probe microscopy of high-coercive iron garnet films Yelena Danishevskaya, V Berzhansky, T Mikhailova, A Krikun, A Nedviga
Electric, Magnetic and Microwave Devices
6-01 Resistive contact MEMS switch in a "hot" operation mode Ilia Uvarov, I Uvarov, V Naumov, A Kupriyanov, O Koroleva, E Vaganova, I Amirov520
6-02 A study of 4H-SiC diode avalanche shaper Sergey Shevchenko, A Afanasyev, B Ivanov, V Ilyin, A Smirnov, A KardoSysoev
6-03 Diffusion theory and optimization of ohmic contacts to n-layers of bipolar nanoheterostructures Aleksei Nezhentsev, A Nezhentsev, V Zemlyakov, V Egorkin, V Garmash
6-04 Numerical simulation of induction heating considering the surface oxidation of titanium samples Aleksandr Fomin, M Fomina, A Voyko, A Zorkin, V Koshuro, I Rodionov
6-05 The influence of the current in the inductor on the temperature of heated titanium samples Marina Fomina, A Fomin, A Voyko, S Kalganova, I Rodionov
6-06 Features of transmission at analog intermediate frequency signals on fiber - optical communication lines in radar station. Daniil Filatov, A Galichina
6-07 Fast electrochemical membrane actuator: Design, fab rication and preliminary testing Pavel Shlepakov, P Shlepakov, I Uvarov, A Postnikov, V Naumov, O Koroleva, M Izyumov, V Svetovoy
6-08 Design and technology optimization of SiC-based RF MEMS switch Anton Lagosh, A Korlyakov

6-09 CNTs-based gas sensor Nikolay Rudyk, O Ilin, M Ilina, A Fedotov	.536
6-10 Conductive channel of microwave generator based on indium antimonide nanowires Andrey Lozovenko, G Gorokh, I Obukhov, E Smirnova	.538
6-11 Electrical properties of polycrystalline materials from the system Cu-As-Ge-Se under high pressure condition Vasilisa Zaikova, V Zaikova, N Melnikova, A Tebenkov	
6-12 Exploring ceramic-based composites as Ka-band absorbers Gleb Gorokhov, D Bychanok, D Meisak, A Plushch, A Sokal	.542
6-13 Investigation of resistive switching of ZnxTiyHfzOi nanocomposite for RRAM element manufacturing	
Roman Tominov, V Smirnov, O Ageev, E Zamburg	
6-15 Optical thermometry based on levelanticrossing in nano-silicon carbide Andrey Anisimov, V A Soltamov, P G Baranov, G V Astakhov, V Dyakonov	.548
6-16 Temperature Effects on the Magnetization and Magnetoimpedance in Ferromagnetic Glass-Covered microwires Azim Uddin, D Abdukarim, N Maqsudsho	
6-17 Non-destructive Testing of Nanomaterials by Using Subminiature Eddy Current Flaw Transducers Vladimir Malikov, V Malikov, A Belyaev, S Dmitriev, A Sagalakov, A Ihkov	
6-18 Influence of current limitation on the adaptive behavior of the memristive nanostructures Dmitry Korolev, A Mikhaylov, A Belov, E Okulich, I Antonov, D Tetelbaum	.554
6-19 Bistable arch-like beams with modulated profile as perspective supporting structures a microelectromenchanical actuator Yakov Enns, E Pyatishev, A Glukhovskoy	
6-20 Effect of temperature passivation on surface traps in the HEMT-transistors based on AlGaN / SiC Anton Evseenkov, S Tarasov, V Tikhomirov, V Zemlyakov	
6-21 Suppression of the self-heating effect in AlGaN/GaN high electron mobility transistor few-layer graphene Vladislav Volcheck,	by
6-22 AlGaAs/GaAs HBTs with C-doped base and undoped emitter-base spacer layer Mikhail Bobrov, N Maleev, A Kuzmenkov, A Vasiljev, S Blokhin, V Egorkin, V Zemlyakov, V Ustinov	.562

Silicon carbide of Ni/6H-SiC and Ti/4H-SiC type Schottky diode current-voltage characteristics modelling

P V Panchenko, S B Rybalka, A A Malakhanov, A A Demidov

Bryansk State Technical University, Brynask, 50 let Oktyabrya 7, Russia

Abstract. Forward current–voltage characteristics of Ni/6H-SiC and Ti/4H-SiC Schottky diode with Ni and Ti Schottky contact have been simulated based on in the physical analytical models based on Poisson's equation, drift–diffusion and continuity equations. On the base of analysis of *I-V* characteristics in terms of classical thermionic emission theory it is shown that the proposed simulation model of Schottky diode corresponds to the "ideal" diode with ideality factor $n\approx1.1$. It is established that effective Schottky barrier height φ_B =1.57 eV for Ni/6H-SiC and φ_B =1.17 eV for Ti/4H-SiC Schottky diode.

1. Introduction

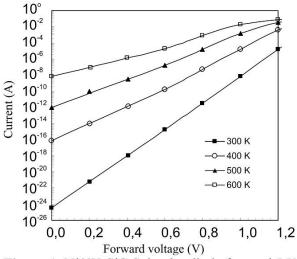
Silicon carbide (SiC) as material for semiconductor electronics has been studied at first in Leningrad (St. Petersburg) by the O.V. Losev's at the A.F. Ioffe Institute at the beginning of the 1930s. Now silicon carbide represents an excellent candidate for high-temperature power electronic device applications because of its high breakdown voltage, low series resistance, and stability under harsh chemical and high temperature conditions [1]. SiC Schottky diodes are of special interest since these unipolar devices avoid reverse recovery effects of bipolar devices, thereby offering higher frequency operation In particular, SiC Schottky diodes for power electronics in future must be produced by domestic company the «GROUP KREMNY L» (Bryansk). It is obviously that for development of component base on the base of SiC studying and optimisation of such important device as Schottky diode it is necessary. Earlier simulation of current-voltage (I-V) characteristics in 4H-SiC Schottky diode with Ni Schottky contact has been made [2]. Therefore in present work simulation of current-voltage (I-V) characteristics in Schottky diode on base of 6H-SiC and 4H-SiC type silicon carbide with Ni and Ti Schottky contact with used of TCAD program has been carried out.

2. Materials and methods

The materials parameters for simulation were following: the concentration of donors (nitrogen) in the substrate equals $N_D^+ = 10^{16} - 10^{18}$ cm⁻³, in the epitaxial layer equals 8×10^{15} , anode material is Ni (nickel) and Ti (titanium), thickness of the epitaxial layer (4H-SiC and 6H-SiC) equals z=15 µm, radius of the structure equals r=200 µm. For simulation model of current-voltage characteristics has been solved electrostatic Poisson's equation in cylindrical coordinates together with continuity equations for electrons and holes. Because of this for calculation current-voltage (I-V) characteristics in Schottky diode was applied of the thermionic emission theory which taking into account of the electron-phonon interaction, quantum-mechanical tunneling through barrier and reduction of barrier height under influence of image force effect [3,4].

3. Results and discussion

For simulation model of current-voltage (*I-V*) characteristics has been solved electrostatic Poisson's equation in cylindrical coordinates together with drift-diffusion and continuity equations. For simulation forward current-voltage characteristics were chosen the following temperature: 300, 400, 500 and 600 K. Simulation results of forward current-voltage characteristics for Ni/4H-SiC and Ti/4H-SiC Schottky diodes in TCAD program are presented in Fig. 1 and Fig. 2.



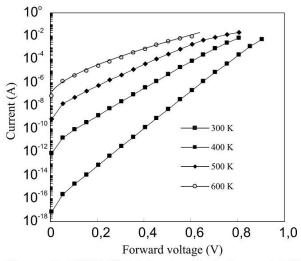


Figure 1. Ni/6H-SiC Schottky diode forward *I-V* characteristics.

Figure 2. Ti/4H-SiC Schottky diode forward *I-V* characteristics.

Then results of forward current-voltage characteristics for Ni/4H-SiC and Ti/4H-SiC Schottky diodes were analyzed in framework of classical diode theory [3-5. to estimate the Schottky diode quality which for good Schottky diode is equal ~1.0÷1.1. In our case the obtained ideality coefficients n are close to good Schottky diode. Because of this it is established that effective Schottky barrier height φ_B =1.57 eV for Ni/6H-SiC and φ_B =1.17 eV for Ti/4H-SiC Schottky diode.

3. Conclusions.

Finally, forward current-voltage (*I-V*) characteristics in Ni/6H-SiC and Ti/4H-SiC Schottky diode with Ni and Ti Schottky contact have been obtained on the base of simulation model in TCAD in framework of the physical analytical models based on Poisson's equation, drift-diffusion and continuity equations. It is shown that forward current-voltage characteristics in terms of the Schottky diode simulation model corresponds to the "ideal" Schottky diode describes in framework of the classical thermionic emission theory with the ideality factor of Schottky diodes is close to good Schottky diode.

Acknowledgements

Authors would like to thank Dr. Surin B.P. for help in carrying out of TCAD simulation. This work was supported by the Russian Ministry of Education (Grant No. 02.G25.31.0201).

References

- [1] Kimoto T, Cooper J A 2014 Fundamentals of Silicon Carbide Technology. Growth, Characteriztion, Devices, and Applications (New York: Wiley–IEEE Press.)
- [2] Rybalka S B, Krayushkina E Yu, Demidov A A, Shishkina O A, Surin B P 2017 Int. J. Physical Research 5 11.
- [3] Shur M 1990 Physics of semiconductor devises (New Jersey: Prentice-Hall Int.)
- [4] Sze S M 1969 Physics of Semiconductor Devices (New York: Wiley-Interscience)
- [5] Rhoderick E H 1978 Metal-Semiconductor Contacts (Oxford: Clarendon Press)